

| | | | | |
|-----------------------------------|---------------------------------------|--|--|-------------|
| Notice of References Cited | Application/Control No. 10/605,319 | | Applicant(s)/Patent Under Reexamination GRIER ET AL. | |
| | Examiner Arnel C. Lavarias | | Art Unit 2872 | Page 1 of 1 |

U.S. PATENT DOCUMENTS

| * | | Document Number Country Code-Number-Kind Code | Date MM-YYYY | Name | Classification |
|---|---|--|-----------------|------------------|----------------|
| | A | US-6,416,190 | 07-2002 | Grier et al. | 359/614 |
| | B | US-6,626,546 | 09-2003 | Grier et al. | 359/614 |
| | C | US-6,737,634 | 05-2004 | Curtis et al. | 250/222.2 |
| | D | US-2004/0021949 | 02-2004 | Grier et al. | 359/614 |
| | E | US-5,939,716 | 08-1999 | Neal, Daniel R. | 250/251 |
| | F | US-5,935,507 | 08-1999 | Morito et al. | 264/482 |
| | G | US-5,986,781 | 11-1999 | Long, Michael D. | 359/30 |
| | H | US- | | | |
| | I | US- | | | |
| | J | US- | | | |
| | K | US- | | | |
| | L | US- | | | |
| | M | US- | | | |

FOREIGN PATENT DOCUMENTS

| * | | Document Number Country Code-Number-Kind Code | Date MM-YYYY | Country | Name | Classification |
|---|---|--|-----------------|---------|------|----------------|
| | N | NONE | | | | |
| | O | | | | | |
| | P | | | | | |
| | Q | | | | | |
| | R | | | | | |
| | S | | | | | |
| | T | | | | | |

NON-PATENT DOCUMENTS

| * | | Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages) |
|---|---|---|
| | U | E. R. Dufresne, D. G. Grier, 'Optical tweezer arrays and optical substrates created with diffractive optics', Rev. Sci. Instru., vol. 69, no. 5, May 1998, pp. 1974-1977. |
| | V | K. Sasaki, M. Koshioka, H. Misawa, N. Kitamura, H. Masuhara, 'Pattern formation and flow control of fine particles by laser-scanning micromanipulation', Opt. Lett., vol. 16, no. 19, October 1, 1991, pp. 1463-1465. |
| | W | |
| | X | |

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.